IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No	10/813,543
Filing Date	
Confirmation No	
Inventor	F. Dan Gealy
Assignee	Micron Technology, Inc.
Group Art Unit	1792
Examiner	Keath T. Chen
Attorney's Docket No	MI22-3685
Title: Method for Reducing Physisorption During Atomic Layer Deposition	

RESPONSE TO AUGUST 1, 2008 FINAL OFFICE ACTION

To:

Mail Stop AF

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

From:

Robert C. Hyta (Tel. 509-624-4276; Fax 509-838-3424)

Wells St. John P.S.

601 W. First Avenue, Suite 1300

Spokane, WA 99201-3828